

**Amendments to the Claims:**

Please cancel Claims 5, 14, 21, and 27 – 29, and amend Claims 1, 6, 10, 15 – 17, and 23 as indicated in the following listing of claims, which replaces all prior versions and listings of claims in the application.

**Listing of Claims:**

1. (Currently Amended) A movable microstructure ~~for steering light, the~~  
~~microstructure~~ comprising:  
    ~~a substrate;~~  
    a first tiltable assembly ~~connected with the~~ formed over a substrate, ~~the first~~  
~~tiltable assembly including a reflective coating;~~  
    a second tiltable assembly ~~connected with~~ formed over the substrate; and  
    first and second electrodes ~~connected with the substrate and~~ respectively  
~~configured~~ positioned relative to the substrate to tilt the first and second tiltable assemblies upon  
activation such that the first and second tiltable assemblies are interdigitated.
2. (Original) The microstructure recited in claim 1 wherein the first tiltable  
assembly is configured as a cantilever arrangement.
3. (Original) The microstructure recited in claim 2 wherein the second tiltable  
assembly is configured as a torsion-beam arrangement.
4. (Original) The microstructure recited in claim 1 wherein the second tiltable  
assembly is configured as a torsion-beam arrangement.
5. (Canceled).

6. (Currently Amended) The microstructure recited in claim 1,  
wherein the first tiltable assembly includes:

a first structural linkage ~~connected with~~ formed over the substrate;

a first structural film supported by the first structural linkage and having a plurality of fingers at an end of the first structural film, ~~with the reflective coating on the first structural film~~; and

wherein the second tiltable assembly includes:

a second structural linkage ~~connected with~~ formed over the substrate; and

a second structural film supported by the second structural linkage and having a plurality of fingers at an end of the second structural film.

7. (Original) The microstructure recited in claim 6 wherein the first and second electrodes comprise polysilicon.

8. (Original) The microstructure recited in claim 6 wherein the first and second structural films comprise polysilicon.

9. (Original) The microstructure recited in claim 6 wherein the first structural linkage has a greater height above the substrate than the second structural linkage.

10. (Currently Amended) A method for fabricating a movable microstructure ~~for steering light~~, the method comprising:

forming a first tiltable assembly ~~on~~ over a substrate, ~~the first tiltable assembly including a reflective coating~~;

forming a second tiltable assembly ~~on~~ over the substrate; and

forming first and second electrodes ~~on the substrate, such first and second electrodes being configured~~ relative to the substrate to tilt the first and second tiltable assemblies upon activation such that the first and second tiltable assemblies interdigitate.

11. (Original) The method recited in claim 10 wherein forming the first tiltable assembly comprises creating a cantilever arrangement.

12. (Original) The method recited in claim 11 wherein forming the second tiltable assembly comprises creating a torsion-beam arrangement.

13. (Original) The method recited in claim 10 wherein forming the second tiltable assembly comprises creating a torsion-beam arrangement.

14. (Canceled).

15. (Currently Amended) The method recited in claim 10,  
wherein forming the first tiltable assembly includes:

forming a first structural linkage ~~on~~ over the substrate;

forming a first structural film on the first structural linkage, the first structural film having a plurality of fingers at an end of the first structural film, ~~with the reflective coating deposited on the first structural film;~~ and

wherein forming the second tiltable assembly includes:

forming a second structural linkage ~~on~~ over the substrate; and

forming a second structural film on the second structural linkage, the second structural film having a plurality of fingers at an end of the second structural film.

16. (Currently Amended) The method recited in claim 15 wherein forming the first structural linkage comprises forming the first structural linkage ~~on~~ over the substrate at a height greater than the second structural linkage.

17. (Currently Amended) A method for operating ~~an optical switch~~ a movable microstructure, the method comprising:

tilting a first assembly by applying a first electrostatic force, the first assembly including:

a first structural linkage ~~connected with~~ formed over a substrate; and  
a first structural film supported by the first structural linkage and having a plurality of fingers at an end of the first structural film; ~~and~~

~~a reflective coating on the first structural film;~~

tilting a second assembly by applying a second electrostatic force, the second assembly including:

a second structural linkage ~~connected with~~ formed over the substrate; and  
a second structural film supported by the second structural linkage and having a plurality of fingers at an end of the second structural film; and

holding the first and second assemblies electrostatically in a fixed position with the fingers of the first and second structural films interdigitated.

18. (Original) The method recited in claim 17 wherein the first assembly is configured as a cantilever arrangement.

19. (Original) The method recited in claim 18 wherein the second assembly is configured as a torsion-beam arrangement.

20. (Original) The method recited in claim 17 wherein the second assembly is configured as a torsion-beam arrangement.

21. (Canceled).

22. (Original) The method recited in claim 17 wherein tilting the first assembly comprises tilting the end of the first structural film having a plurality of fingers towards the substrate and tilting the second assembly comprises tilting the end of the second structural film having a plurality of fingers away from the structural assembly.

23. (Currently Amended) A movable microstructure ~~for steering light~~, the microstructure comprising:  
**~~support means;~~**  
tiltable micromirror means ~~connected with the~~ formed over a support means;  
tiltable snare means connected with the support means; and  
means for generating electrostatic forces for tilting the tiltable micromirror means and the tiltable snare means into an interdigitated configuration.

24. (Original) The microstructure recited in claim 23 wherein the tiltable micromirror means comprises cantilever means.

25. (Original) The microstructure recited in claim 28 wherein the snare means comprises torsion-beam means.

26. (Original) The microstructure recited in claim 23 wherein the micromirror means comprises torsion-beam means.

27. – 29. (Canceled).